

IFW



Docket No.: 060188-0702

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
Akio MISAKA	:	Confirmation Number: 8679
Application No.: 10/717,598	:	Group Art Unit: 1756
Filed: November 21, 2003	:	Examiner: ROSASCO, STEPHEN D

For: PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND MASK
DATA CREATION METHOD

RESPONSE TO NOTICE OF NON-COMPLIANT AMENDMENT (37 CFR 1.121)
AND AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Notice of Non-Complaint Amendment (37 CFR 1.121) mailed April 27, 2006. Please note an Amendment and petition for a one-month extension of time up to and including April 19, 2006, were originally filed on April 19, 2006. Please note, the status of claim 11 is now identified as "Currently Amended".

The following amendments and remarks are submitted in response to the Office Action dated December 19, 2005.

Application No.: 10/717,598

AMENDMENT TO THE TITLE:

Please amend the title as follows:

~~PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND
MASK DATA CREATION METHOD~~